

Three-Motors Configuration for Adjusting Wafer Tilt and Focus

ABSTRACT

A system includes a first interferometer to measure the shape of a first side of a semiconductor wafer, a pallet to hold the semiconductor wafer and expose the first side of the semiconductor wafer to the first interferometer, and three motors coupled to the pallet. The three motors include a first motor coupled to the pallet at a first position, a second motor coupled to the pallet at a second position, and a third motor coupled to the pallet at a third position.